

Notice of References Cited	Application/Control No. 09/842,370	Applicant(s)/Patent Under Reexamination WIESLER ET AL.	
	Examiner Chongshan Chen	Art Unit 2162	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,466,945	10-2002	Goh et al.	707/102
	B	US-5,761,064	06-1998	La et al.	700/110
	C	US-			
	D	US-			
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	F	US-			
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	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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	S					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Assessment of the performance of a reticle stocker with integrated database and the productivity gain obtained in a submicron ASIC waferfab, http://www.sea.rl.ac.uk/OldSEA/oldpubs/Retimatic/
	V	Denise Dillon Harris, Automated Reticle Management Increases Efficiency, Throughput, and Capital Investment Utilization, http://www.semiconductorfabtech.com/features/lithography/articles/body3.195.php3
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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